

Notice of References Cited	Application/Control No. 10/622,607		Applicant(s)/Patent Under Reexamination CHEN ET AL.	
	Examiner Matthew W. Such		Art Unit 2891	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,417,076	07-2002	Holscher et al.	438/462
*	B	US-6,291,315	09-2001	Nakayama et al.	438/459
	C	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Merriam-Webster's Collegiate Dictionary. 10th ED. (1997): entry for "lithography".			
	V	Quirk, Michael and Serda, Julian. SEMICONDUCTOR MANUFACTURING TECHNOLOGY. Prentice-Hall, Inc., Upper Saddle River, New Jersey (2001): page 304.			
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.